

**EXHIBIT B.03**  
**U.S. Patent No. 7,604,716**

References cited herein:

- U.S. Patent No. 7,604,716 (“716 Patent”)
- D.V. Mozgrin, *et al*, High-Current Low-Pressure Quasi-Stationary Discharge in a Magnetic Field: Experimental Research, Plasma Physics Reports, Vol. 21, No. 5, 1995 (“Mozgrin”)
- A. A. Kudryavtsev, *et al*, Ionization relaxation in a plasma produced by a pulsed inert-gas discharge, Sov. Phys. Tech. Phys. 28(1), January 1983 (“Kudryavtsev”)
- U.S. Pat. No. 6,190,512 (“Lantsman”)
- Milton Ohring, *The Material Science of Thin Films*, Academic Press, 1992 (“Ohring”)
- Donald L. Smith, *Thin-Film Deposition: Principles & Practice*, McGraw Hill, 1995 (“Smith”)

| Claims 19 and 20  | Mozgrin in view of Kudryavtsev and Lantsman   |
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| 14. A method for generating a strongly-ionized plasma, the method comprising: | <p>The combination of Mozgrin with Kudryavtsev discloses a method for generating a strongly-ionized plasma.</p> <p>‘716 Patent at claim 24 (“wherein the peak plasma density of the strongly-ionized plasma is greater than about <math>10^{12} \text{ cm}^{-3}</math>”)</p> <p>Mozgrin at Fig 1</p> <p>Mozgrin at 400, right col, ¶ 4 (“To study the high-current forms of the discharge, we used two types of devices: a planar magnetron and a system with specifically shaped hollow electrodes.”)</p> <p>Mozgrin at 401, right col, ¶2 (“For pre-ionization ... the initial plasma density in the <math>10^9 - 10^{11} \text{ cm}^{-3}</math> range.”)</p> <p>Mozgrin at 409, left col, ¶ 4 (“The implementation of the high-current magnetron discharge (regime 2) in sputtering ... plasma density (exceeding <math>2 \times 10^{13} \text{ cm}^{-3}</math>.”)</p> <p>Mozgrin at 409, left col, ¶5 (“The high-current diffuse discharge (regime 3) is useful for producing large-volume uniform dense plasmas <math>n_i \cong 1.5 \times 10^{15} \text{ cm}^{-3}</math> ...”).</p> |
| a. ionizing a feed gas in a chamber to form a weakly-ionized                  | The combination of Mozgrin with Kudryavtsev discloses ionizing a feed gas in a chamber to form a weakly-ionized plasma that substantially eliminates the probability of developing an electrical  |

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| <p>plasma that substantially eliminates the probability of developing an electrical breakdown condition in the chamber; and</p>   | <p>breakdown condition in the chamber.</p> <p>‘716 Patent at 5:14-15 (“The weakly-ionized plasma 232 is also referred to as a pre-ionized plasma.”)</p> <p>‘716 Patent at claim 23 (“wherein the peak plasma density of the weakly-ionized plasma is less than about <math>10^{12} \text{ cm}^{-3}</math>”)</p> <p>Mozgrin at Figs. 1, 2, 3, 6, 7</p> <p>Mozgrin at 401, left col, ¶ 1 (“The [plasma] discharge had an annular shape and was adjacent to the cathode.”)</p> <p>Mozgrin at 401, left col, ¶ 4 (“[A]pplying a square voltage pulse to the discharge gap which was filled up with either neutral or pre-ionized gas.”)</p> <p>Mozgrin at 402, right col, ¶2 (“Figure 3 shows typical voltage and current oscillograms.... Part I in the voltage oscillogram represents the voltage of the stationary discharge (pre-ionization stage).”)</p> <p>Mozgrin at 401, right col, ¶2 (“[f]or pre-ionization, we used a stationary magnetron discharge; ... provided the initial plasma density in the <math>10^9 - 10^{11} \text{ cm}^{-3}</math> range.”)</p> <p>Mozgrin at 400, right col, ¶ 3 (“We investigated the discharge regimes in various gas mixtures at <math>10^{-3} - 10</math> torr...”)</p> <p>Mozgrin at 402, ¶ spanning left and right cols (“We studied the high-current discharge in wide ranges of discharge current...and operating pressure...using various gases (Ar, N<sub>2</sub>, SF<sub>6</sub>, and H<sub>2</sub>) or their mixtures of various composition...”)</p> |
| <p>b. supplying an electrical pulse across the weakly-ionized plasma that excites atoms in the weakly-ionized plasma, thereby generating a strongly-ionized plasma without developing an electrical breakdown</p> | <p>The combination of Mozgrin with Kudryavtsev discloses supplying an electrical pulse across the weakly-ionized plasma that excites atoms in the weakly-ionized plasma, thereby generating a strongly-ionized plasma without developing an electrical breakdown condition in the chamber.</p> <p>‘716 Patent at claim 23 (“wherein the peak plasma density of the weakly-ionized plasma is less than about <math>10^{12} \text{ cm}^{-3}</math>”)</p> <p>‘716 Patent at claim 24 (“wherein the peak plasma density of the strongly-ionized plasma is greater than about <math>10^{12} \text{ cm}^{-3}</math>”)</p>   |

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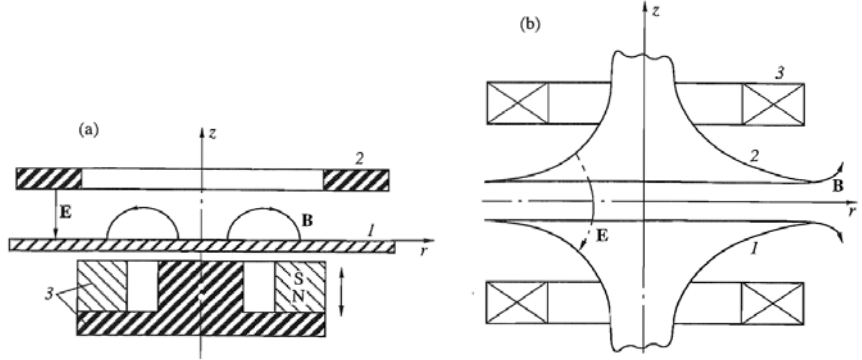
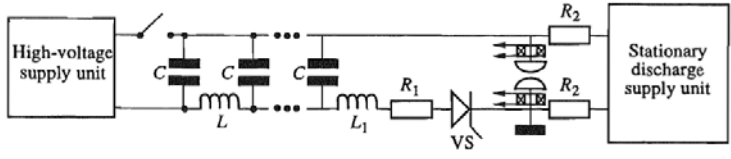
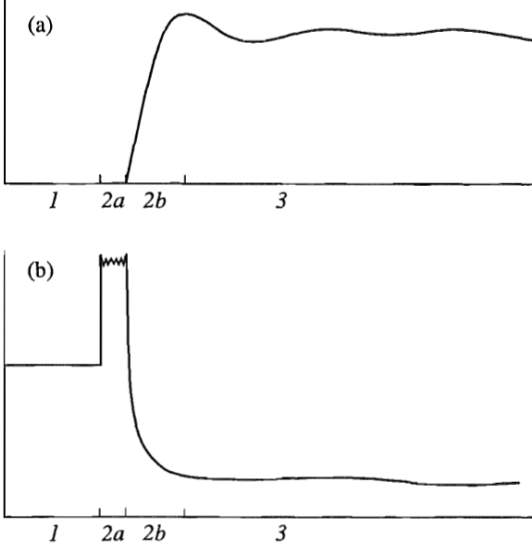
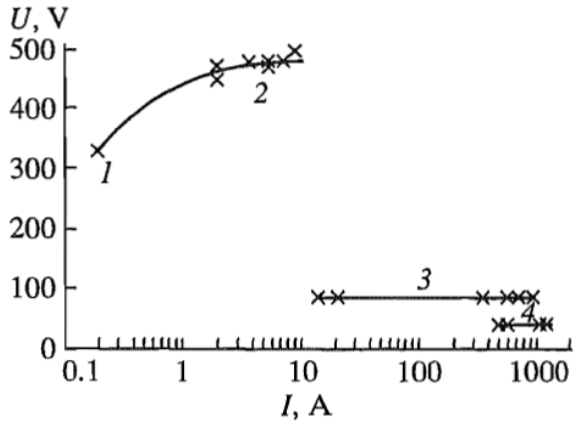
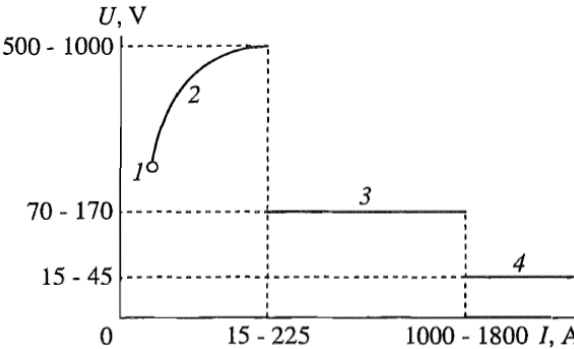
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| <p>condition in the chamber.</p> | <p>Mozgrin at Fig. 1</p>  <p><b>Fig. 1.</b> Discharge device configurations: (a) planar magnetron; (b) shaped-electrode configuration. (1) Cathode; (2) anode; (3) magnetic system.</p> <p>Mozgrin at Fig. 2</p>  <p><b>Fig. 2.</b> Discharge supply unit.</p> <p>Mozgrin at Fig. 3</p> |

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|                  |  <p data-bbox="544 871 1039 934"><b>Fig. 3.</b> Oscillograms of (a) current and (b) voltage of the quasi-stationary discharge (50 <math>\mu</math>s per div., 180 A per div., 180 V per div.).</p> <p data-bbox="511 976 1339 1081">Mozgrin at 402, right col, ¶ 2 (“Part 1 in the voltage oscillogram represents the voltage of the stationary discharge (pre-ionization stage).”)</p> <p data-bbox="511 1123 1412 1186">Mozgrin at 401, right col, ¶2 (“For pre-ionization ... the initial plasma density in the <math>10^9 - 10^{11} \text{ cm}^{-3}</math> range.”)</p> <p data-bbox="511 1207 1404 1312">Mozgrin at 401, right col, ¶ 1 (“Thus, the supply unit was made providing square voltage and current pulses with [rise] times (leading edge) of 5 – 60 <math>\mu</math>s...”).</p> <p data-bbox="511 1354 1380 1417">Mozgrin 403, right col, ¶4 (“Regime 2 was characterized by intense cathode sputtering...”) (emphasis added).</p> <p data-bbox="511 1459 1412 1564">Mozgrin at 409, left col, ¶ 4 (“The implementation of the high-current magnetron discharge (regime 2) in sputtering ... plasma density (exceeding <math>2 \times 10^{13} \text{ cm}^{-3}</math>).”)</p> <p data-bbox="511 1606 1339 1711">Mozgrin at 409, left col, ¶5 (“The high-current diffuse discharge (regime 3) is useful for producing large-volume uniform dense plasmas <math>n_i \cong 1.5 \times 10^{15} \text{ cm}^{-3}</math>...”)</p> <p data-bbox="511 1753 1404 1858">Mozgrin at 400, left col, ¶ 3 (“Some experiments on magnetron systems of various geometry showed that discharge regimes which do not transit to arcs can be obtained even at high currents.”)</p> <p data-bbox="511 1879 1364 1900">Mozgrin at 400, right col, ¶ 1 (“A further increase in the discharge</p> |

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|                  | <p>currents caused the discharges to transit to the arc regimes...”).</p> <p>Mozgrin at 404, left col, ¶ 3 (“The parameters of the shaped-electrode discharge...transit to arc regime 4, could be well determined... The point of the planar-magnetron discharge transit to the arc regime was determined by discharge voltage and structure changes...”).</p> <p>Mozgrin at 404, left col, ¶ 4 (“If the current was raised above 1.8 kA or the pulse duration was increase to 2 – 10 ms, an instability development and discharge contraction was observed.”).</p> <p>Mozgrin at Fig. 4</p>  <p><b>Fig. 4.</b> Current-voltage characteristic of the quasi-stationary discharge with shaped electrodes in argon, <math>p = 0.1</math> torr; <math>B = 0.4</math> kG.</p> <p>Mozgrin at Fig. 7</p>  <p><b>Fig. 7.</b> Generalized ampere-voltaic characteristic CVC of quasi-stationary discharge.</p> <p>Mozgrin at 401, ¶ spanning left and right columns (“Designing the [pulsed supply] unit, we took into account the dependences which had been obtained in [Kudryavtsev] of ionization relaxation on pre-</p> |

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